

DRAFT

DO NOT ENTER

10/22/02

Attorney Docket: 622/48561
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: MARTIN DUBS ET AL.
Serial No.: 09/484,421 Group Art Unit: 1753
Filed: JANUARY 18, 2000 Examiner: G. CANTELMO
Title: SPUTTER CHAMBER AS WELL AS VACUUM TRANSPORT
CHAMBER AND VACUUM HANDLING APPARATUS WITH
SUCH CHAMBERS

AFTER-FINAL REPLY UNDER 37 CFR §1.116
EXPEDITED HANDLING REQUESTED

Commissioner for Patents
Washington, D.C. 20231

Sir:

The following is responsive to the Office Action mailed on or about April
18, 2002.

IN THE CLAIMS:

A version with markings to show the changes made is attached to this
Reply.

Please amend Claims 35, 47, 48, 50 and 58 as follows:

35. (Amended) Sputtering chamber comprising at least one sputtering
source with a new sputter surface at least approximately symmetrical with
respect to a first axis oriented perpendicular to said new sputter surface, a